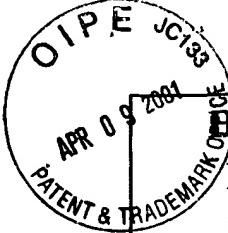


**INFORMATION
DISCLOSURE
STATEMENT**

	Atty. Docket No.: 110.01420101	Serial No.: 09/691,006
	Applicant(s): James R. Leger et al.	
	Filing Date: October 18, 2000	Group: 2877

U.S. PATENT DOCUMENTS

Examiner Initial	Document Number	Date	Name	Class	SubClass	Filing Date If Appropriate
AD	5,042,951	08/27/91	Gold et al.			10/18/2000
AD	5,910,841	06/08/99	Masao			
AD	5,963,326	10/05/99	Masao			10/05/99

FOREIGN PATENT DOCUMENTS

	Document Number	Date	Country	Class	SubClass	Translation	
						Yes	No
	NONE						

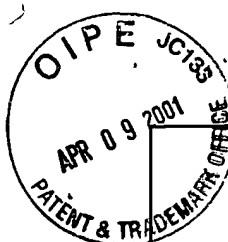
OTHER DOCUMENTS (Including Authors, Title, Date, Pertinent Papers, etc.)

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AD	Erman et al., "Spatially resolved ellipsometry", <u>J. Appl. Phys.</u> , 60(3):859-873 (1986).
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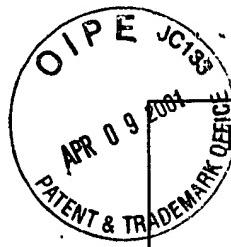
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